Author(s): Z. Giedraityte, J. Sainio, D. Hagen and M. Karppinen
Title: Luminescent metal-nucleobase network thin films by atomic/molecular layer deposition
Year: 2017
Version: Final published version

Please cite the original version:


This publication is included in the electronic version of the article dissertation: Giedraityte, Zivile. Novel Inorganic-Organic Luminescent Materials by Atomic/Molecular Layer Deposition. Aalto University publication series DOCTORAL DISSERTATIONS, 64/2018.
Luminescent Metal-Nucleobase Network Thin Films by Atomic/Molecular Layer Deposition

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ABSTRACT: Controlled molecular deposition of natural organic molecules such as nucleobases (NBs) into well-defined thin films represents progress toward exciting new nanomaterials. The strongly emerging atomic/molecular layer deposition (ALD/MLD) technique provides us with an elegant way to realize the depositions through gas phase with atomic/molecular level accuracy. In the resultant thin films the organic molecules are bound together not only with hydrogen bonds but also via metal cation linkers and are likely to exhibit novel properties. Here we demonstrate the ALD/MLD of such thin films with monovalent sodium, divalent barium, or trivalent lanthanum as the metal linker and uracil or adenine as the NB component. Our metal-NB thin films are homogeneous, smooth, and in the case of sodium and barium also crystalline showing intense photoluminescence. We discuss the impact of the size and charge of the metal cation on the growth and properties of the films.

1. INTRODUCTION

Combining biobased organic components with inorganics into advanced functional materials with unorthodox (synergistic or collective) physical properties could be transformational for the next-generation applications in, e.g., electronics, optics, or sensing. However, new approaches are required to realize the dream of rationally constructing such materials from different building blocks into desired functionality.1

Deoxyribonucleic acid (DNA) and ribonucleic acid (RNA) are widely studied as exciting sustainable biobased precursors e.g., nucleic acids sensors.13 It should be emphasized that the interest in nucleic acid interactions is not only uracil but also adenine that, unlike uracil, does not have hydroxide groups, see Figure 1. Besides the new ALD/MLD processes, we report photoluminescence properties for our next-generation devices as they can be obtained both naturally and synthetically.

The relatively small size of the NB molecules is a clear advantage considering the possible routes to combine the bioorganic component with the inorganic component for the hybrid material, as it allows the sublimation of NBs to gas phase and thereby the use of the most advanced gas-phase thin-film deposition techniques originally developed for inorganic materials. Indeed, we recently demonstrated the fabrication of crystalline sodium-uracil thin films14 using the strongly emerging combined atomic and molecular layer deposition (ALD/MLD) technique.14−19 On the other hand, in our recent works, we have also developed novel ALD/MLD processes for other types of crystalline hybrid thin films based on alkali (Li) and alkaline earth (Ca) metals having an eye on potential Li-ion microbattery50 and metal organic framework21,22 applications, but the work on the Na-uracil thin films was the first ALD/MLD work involving NBs. In the present work we aim to extend the approach from monovalent alkali metal species to divalent alkaline earth (Ba) and trivalent lanthanide (La) species as the metal constituent in metal-NB thin films; our anticipation is that not only the cation valence but also the larger size of Ba and La in comparison to Na might affect the metal-nucleobase coordination and thereby possibly also the properties of the films. For the NB constituent we investigate not only uracil but also adenine that, unlike uracil, does not have hydroxide groups, see Figure 1. Besides the new ALD/MLD processes, we report photoluminescence properties for our metal-NB thin films.

2. EXPERIMENTAL SECTION

The hybrid Na, Ba, and La-nucleobase thin films were grown in a commercial ALD reactor (F-120 by ASM Microchemistry Ltd.). As precursors, in-house synthesized Na(thd), Ba(thd)2, and La(thd)3 (thd: 2,2,6,6-tetramethyl-3,5-heptanediionate) and commercial uracil and adenine (Sigma-Aldrich) were used; these solid precursors were sublimated from open precursor boats at the following temperatures: Na(thd) 195 °C, Ba(thd)2 205 °C, La(thd)3 167 °C, uracil 235 °C, and adenine 255 °C.
Nitrogen (99.999%; Schmidlin UHPN 3000 N\textsubscript{2} generator) was used as a carrier gas for the precursors and also for purging the reactor chamber after each precursor pulse, and its pressure was kept at 2−4 mbar during the film deposition. As the first step of process optimization, the precursor and purge pulse lengths were investigated for the Ba(thd\textsubscript{2}) + uracil process within 1.5−3.5 s Ba(thd\textsubscript{2})/2−7 s N\textsubscript{2}/2−4 s uracil/4−8 s N\textsubscript{2}. Based on these depositions and some preliminary experiments with the other precursor pairs the pulse and purge periods were fixed at the following values for all other depositions: 1.5 s metal precursor/2 s N\textsubscript{2}/2 s NB/4 s N\textsubscript{2}. The first depositions were carried out at different temperatures from 260 to 320 °C, but for the final depositions the temperature was fixed to 300 °C for the better comparison. Both silicon and quartz substrates were used.

For the film thickness and density evaluation, we used X-ray reflectivity measurements (XRR; Analytical Pert MPD Pro Alfa; Cu K\textsubscript{α1} radiation). Grazing incidence X-ray diffraction (GIXRD) measurements were performed with the same equipment to address the crystallinity of the films. Surface morphology was investigated with atomic force microscopy (AFM; Vecco Dimension 51000 Scanning Probe Microscope; Nanoscope Controller, Digital Instruments, Inc.; Nanoscope Analysis 1.5 Software). Moreover, for the Na-based films which turned out to be rougher than the other films, the cantilever AFM tip jump was used to estimate the film thickness (instead of the XRR data).\textsuperscript{14}

Chemical composition and bonding characteristics of the films were investigated by Fourier transform infrared spectroscopy (FTIR; Nicolet 380, ThermoFisher Scientific) and X-ray photoelectron spectroscopy (XPS; Kratos Axis Ultra spectrometer). In both cases our uracil precursor powder was used as a reference sample. The FTIR spectra we recorded in transmission mode with a 1 cm\textsuperscript{−1} resolution and averaged over a minimum of 64 scans. The XPS spectra were acquired with monochromated Al K\textsubscript{α1} radiation and charge neutralization. High resolution spectra were measured using a pass energy of 20 eV, an X-ray power of 75 W, and an analysis area of approximately 700 × 300 μm\textsuperscript{2}. The nitrogen 1s peak of uracil at 400.9 eV was used as a reference to correct for charging the samples. Due to surface oxidation, for Ba-adenine the spectra were collected after sputtering away ca. 3 nm of the film with an Ar gas cluster ion source (Kratos Analytical; Ar\textsubscript{500} clusters; 10 keV).

Figure 1. Structures of the nucleobase precursor molecules employed: uracil C\textsubscript{4}H\textsubscript{4}N\textsubscript{2}O\textsubscript{2} and adenine C\textsubscript{5}H\textsubscript{5}N\textsubscript{5}.

Figure 2. Optimization of the deposition parameters and confirmation of the ALD/MLD type film growth for our Ba(thd\textsubscript{2}) + uracil process (estimated error bars within the datum point marks): (A) GPC at different deposition temperatures; (B) GPC with different precursor pulse lengths; (C) examples of XRR curves for films deposited with different numbers of ALD/MLD cycles; (D) linear dependence of the film thickness on the number of ALD/MLD cycles. In panels B−D the deposition temperature was 300 °C.

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For the characterization of our metal-nucleobase thin films for their photoluminescence properties both excitation and emission spectra were collected by QuantMaster 40 spectrofluorometer from Photon Technology International; in these measurements the second order peaks were eliminated by using a 400–495 nm long pass filter (FGL400, FGL495, Thorlabs) in the emission channel. The emission and excitation slits were set to 1.25 nm, and the fluorescence spectra were corrected by using instrument’s excitation and emission corrections provided by the manufacturer. Finally, UV−vis absorption spectra were measured for the samples using PerkinElmer Lambda 950 UV/vis/NIR absorption spectrophotometer.

Finally we deposited Ba-uracil on porous substrates of anodized aluminum oxide (AAO; InRedox; 1 μm deep, 300 nm pore diameter). These depositions were carried out at 300 °C for 250 ALD/MLD cycles of the pulse sequence, 1.5 s Ba(thd)2/2 s N2/2 s uracil/4 s N2, to target the film thickness of 70.8 nm. Scanning electron microscopy (SEM; Zeiss Sigma VP microscope; secondary electron detector at 2.5 kV; Carl Zeiss Microscopy Ltd.) images were taken to investigate the conformity of the coatings.

3. RESULTS AND DISCUSSION
Among the different metal precursor and NB precursor pairs tested, we optimized the ALD/MLD thin-film growth parameters most thoroughly for the Ba(thd)2 + uracil process, as summarized in Figure 2. An almost constant growth-per-cycle (GPC) value of ~2.8 Å/cycle was observed within the entire deposition temperature range studied, i.e., 260−320 °C, and also essentially independent of the lengths of the precursor pulses. For the rest of experiments we fixed the deposition temperature at 300 °C and used the following pulse/purge lengths in our ALD/MLD cycle: 1.5 s Ba(thd)2/2 s N2/2 s uracil/4 s N2. This process yielded a linear dependence for the film thickness on the number of ALD/MLD cycles, demonstrating that the thickness indeed can be controlled by the number of ALD/MLD cycles. With these characteristics we can conclude that our Ba(thd)2 + uracil process fulfils the basic criteria considered for an ideal ALD/MLD process. Moreover, based on a less systematic mapping of the deposition parameters for the other precursor combinations, we could conclude that the aforementioned parameters yielded homogene-
La(thd)$_3$ + NB processes (1.6 and 1.4 Å/cycle for uracil and adenine, respectively) are significantly lower than the values for the two Ba(thd)$_2$ + NB processes (3.0 and 3.4 Å/cycle) which in turn are lower than the values for the two Na(thd) + NB processes (4.8 and ∼10 Å/cycle). This trend strongly suggests that the growth rate is apparently controlled by steric hindrance of the bulky thd ligands of the metal precursors, such that the GPC value decreases when the number of these ligands increases in the order of Na(thd)$_3$, Ba(thd)$_2$, and La(thd)$_3$. 

For the chemical composition of the films, a rough estimation can be obtained from the XPS survey spectra collected for the Ba-uracil and Ba-adenine films, see Figure 4.

![Figure 4. XPS survey spectra for the Ba-uracil and Ba-adenine thin films as well as for the uracil and adenine precursors for comparison.](https://example.com/figure4.png)

First of all, no other elements than expected were found in the samples. The concentrations (calculated from peak areas of high resolution spectra; in at-%) for uracil C$_4$H$_4$N$_2$O$_2$ (55 C, 24 N, 21 O) and Ba-uracil (53 C, 15 N, 25 O, 7 Ba) are nearly stoichiometric and would suggest bonding of one barium atom per uracil molecule in our Ba-uracil film. The somewhat decreased proportion of nitrogen found for Ba-uracil could be at least partly due to carbon and oxygen contamination on the thin-film surface. For adenine C$_5$H$_5$N$_5$O (52 C, 48 N, 0.2 O) and Ba-adenine (40 C, 36 N, 18 Ba, 6 O) similar carbon and oxygen excess/contamination is seen as well. Nevertheless, we may estimate the Ba:adenine ratio at around two in our Ba-adenine thin film. The density for the Ba-uracil and Ba-adenine films was determined to be 2.6 and 2.0 g/cm$^3$, respectively, from XRR measurements.

To get insights into the types of chemical bonding in different metal-NB materials, we carried out FTIR measurements for all our hybrid thin films as well as for the uracil and adenine precursors for comparison. The spectra are shown in Figure 5. We first discuss the metal-uracil films. Overall, it can be seen that the spectra for all three metal-uracil films show many common features: the Ba- and La-uracil spectra are nearly identical, whereas the Na-uracil spectrum is somewhat different. From literature related to uracil-based metal complexes it is known that C$\equiv$O and C$\equiv$O are the most preferable binding sites for uracil.\textsuperscript{23} This seems to be the case also in our metal-uracil thin films. Namely, the bands due to v(C$\equiv$O) and v(C$\equiv$O+C$\equiv$C) seen for pure uracil at 1710 and 1675 cm$^{-1}$, respectively, essentially disappear for Ba- and La-uracil indicating that both C$\equiv$O and C$\equiv$O are strongly involved in bonding. Also for Na-uracil these bands get weaker in intensity; moreover, the 1710 cm$^{-1}$ band due to v(C$\equiv$O) is shifted to 1699 cm$^{-1}$.

In the 1800–1300 cm$^{-1}$ region featuring the N1–H and N3–H stretches for the pure uracil, it is seen that changes take place for all three thin films as these peaks are shifted in each case. Finally, the O–H and N–H stretches seen in the 3000 cm$^{-1}$ apparently due to hydrogen bonding.\textsuperscript{24} Hence we may conclude that in all three metal-uracil thin films all four functional sites of uracil, i.e., C2$\equiv$O, C4$\equiv$O, N1–H, and N3–H, are involved in bonding; whether these bonds are metal bonds or hydrogen bonds in each case remains somewhat ambiguous, though.

Then we discuss the FTIR data of our adenine-based samples. First of all, it seems that like in the case of uracil, also for the adenine series the Ba- and La-adenine spectra are more similar and the Na-adenine spectrum somewhat different. Nevertheless, for all three metal-adenine films the peak due to −NH$_2$ at 1670 cm$^{-1}$ for pure adenine\textsuperscript{25} moves upon the nucleobase-metal bond formation, to 1644 cm$^{-1}$ for Na-adenine and to 1634 cm$^{-1}$ for Ba- and La-adenine, confirming that the amino group is involved in bonding in all these films. Then, the signal at 1503 cm$^{-1}$ assigned to N7 is shifted to 1542 cm$^{-1}$ in the case of Na-adenine and to 1539 cm$^{-1}$ for Ba- and La-adenine films, which shows that in all three materials the metal cation may bond to N7. In addition, the band at 1417.5 cm$^{-1}$ (C4N9) shifts to 1379 cm$^{-1}$ in the case of Na-adenine and to 1378 cm$^{-1}$ for Ba- and La-adenine thin films which shows that all three metal-adenine films may bind through N9 as well. On the other hand, only for Na-adenine an additional peak is observed at 1475 cm$^{-1}$ related to binding through N1.

To get additional insights into the bonding, we carried out high-resolution XPS measurements for our Ba-uracil sample at the N 1$s$, C 1$s$, and O 1$s$ and Ba 1$s$ regions; the spectra are shown in Figure 6 together with the corresponding spectra for the uracil precursor for comparison. In the latter case the features seen perfectly agree with previous literature.\textsuperscript{26} Namely, the two inequivalent nitrogen atoms N1 and N3 of uracil are observed as one peak at 400.9 ± 0.1 eV in the N 1$s$ spectrum, and the two oxygen atoms as one peak at 532.0 ± 0.1 eV in the O 1$s$ spectrum.\textsuperscript{27} The different carbon atoms on the other hand are resolved in the C 1$s$ spectrum. For Ba-uracil, the Ba 3$d_{3/2}$ peak observed at 780.7 ± 0.1 eV is consistent with various barium bonding environments, independent of the oxidation state of barium, it being Ba(II) or Ba(0).\textsuperscript{28} The oxygen 1$s$ peak is found at 532.0 ± 0.1 eV, i.e., essentially at the same energy as in the uracil reference. The most informative observation is that a new additional nitrogen peak appears at 399.1 eV in bonding. Also for Na-uracil these bands get weaker in intensity; moreover, the 1710 cm$^{-1}$ band due to v(C$\equiv$O) is shifted to 1699 cm$^{-1}$.
neously CS seems to have been shifted to higher binding energies, suggesting that also other atoms could be involved in bonding. Earlier we revealed for our Na-uracil films similar although somewhat smaller shifts but suggesting toward the deprotonation of N3. Hence, it is clear that in our metal-uracil thin films the metal ion is bonded not only to the C=O site(s) but also to the N atom(s). It should also be noted that in the N 1s spectrum more than half of the nitrogen found in the sample appears to be deprotonated. The XPS signal is however strongly surface sensitive so this ratio will also depend on the orientation of the uracil molecule with respect to the surface. To conclude our findings from the FTIR and XPS data for the bonding schemes in the different metal-NB thin films, it seems that different combinations of metal–oxygen, metal–nitrogen, and hydrogen bonds are involved. Additionally, we like to mention here that all of the metal-NB thin films investigated were found to be extremely stable even after long storage periods in open air. In particular, the La-uracil films could even be immersed in water; this extreme stability of La-uracil films is in line with another interesting observation for the same films, i.e., hydrophobicity with contact angle around 130°.

To discuss the optical properties of our metal-NB thin films we first show in the two upper panels of Figure 7 the UV absorption spectra for the metal-uracil and metal-adenine thin films, and also for the NB precursors for comparison. The well-known π−π transition is seen at 262 and 260 nm for uracil and adenine, respectively. For all of the metal-NB thin films the absorption peak has been shifted toward the higher wavelengths, to 275/272 nm for Na-uracil/adenine and to 277/275 nm for both Ba- and La-uracil/adenine. Furthermore, for the metal-adenine films an additional absorption peak is seen at 320 nm for Na-adenine, at 378 nm for Ba-adenine, and at 371 nm.
for La-adenine. Interestingly, for the two Na-based films the absorption peaks show long spectral trails extending to the visible wavelength range. This was discussed in the case of Na-uracil in our previous works and tentatively ascribed to different localized LUMO states over a certain energy range. Apparently a somewhat similar phenomenon is here seen also for Na-adenine but not for the Ba-NB and La-NB films.

Photoluminescence excitation and emission spectra for all of the metal-NB thin-film samples are shown in the two lower panels of Figure 7. For both the uracil- and adenine series, a similar observation can be made. That is, while the spectra for Na-NB are more complex, those for Ba- and La-NB are qualitatively very similar, showing emission at the green wavelengths up to ∼550 nm. However, the intensities are essentially lower for the La-NB films in comparison to those for Ba-NB. Then, for both the Na-NB films an intense fluorescence emission is seen which moreover strongly depends on the excitation wavelength. Very recently we thoroughly investigated this behavior for our Na-uracil films with time-resolved measurements and showed that the phenomenon is caused by a so-called red-edge excitation shift (REES) effect.29 Similar experiments are planned for Na-adenine as well but not within the scope of the present work.

Finally, in order to demonstrate the suitability of our new metal-NB ALD/MLD processes for conformal coating of complex surface structures we deposited Ba-uracil films on porous anodized aluminum oxide substrate using the same deposition parameters as used in the case of flat substrates. Indeed, as can be seen from the SEM image in Figure 8 the pore walls and the bottom are completely covered with a homogeneous Ba-uracil thin film.

4. CONCLUSIONS

In this work, we established a novel family of hybrid metal-nucleobase thin-film materials realized using the emerging ALD/MLD technique as a state-of-the-art synthesis tool. Our primary aim was to learn how the size and charge of the metal cation affect the growth and properties of the films. For this systematic study we selected monovalent Na, divalent Ba, and...
trivalent La as the metal constituents and uracil and adenine as the NB constituents. For all six metal-NB combinations studied, smooth and homogeneous thin films were readily obtained in a highly controlled manner and with appreciably high growth rates.

The growth-per-cycle rate was found to be controlled by steric hindrance of the bulky metal-precursor ligands, the GPC value decreasing with increasing number of these ligands in the order of Na(thd), Ba(thd)2, and La(thd)3. Our tentative belief is that these bulky ligands may also hinder the in situ crystallization of the films, as our Na-NB films were found to be highly crystalline, Ba-NB partly crystalline, and La-NB films completely amorphous. Hence, in order to deposit crystalline ALD/MLD films for the higher-valent metal species it could be advantageous to look for precursors with as small ligands as possible.

The metal-nucleobase thin films were also characterized for their basic optical properties. In particular, both the Na-NB and Ba-NB films were found to show intense photoluminescence in blue and green wavelengths. Moreover, new phenomena were observed including the excitation-dependent emission, the details of which should be elaborated in future studies.

Our work is significant from the application point of view as well, because the ALD/MLD technique used for the synthesis permits a one-step straightforward method in producing uniform luminescent thin films with precisely controlled thicknesses. Moreover, we carried out preliminary tests on porous substrates to demonstrate that the new ALD/MLD processes yield, as expected, highly conformal coatings even on complex substrate architectures. Such luminescent nanostructures are in high demand for many advanced applications, such as sensors and organic light emitting diodes.

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Notes
The authors declare no competing financial interest.

ACKNOWLEDGMENTS

The present work has received funding from the European Research Council under the European Union’s Seventh Framework Programme (FP/2007-2013)/ERC Advanced Grant Agreement (No. 339478) and Academy of Finland (No. 296299). This work made use of the Aalto University Framework Programme (FP/2007-2013)/ERC Advanced Grant Agreement (No. 296299). This work made use of the Aalto University Nanomicroscopy Center (Aalto-NMC) premises. Dr. Nikolay Houbenov is thanked for his guidance in AFM experiments.

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17544
DOI: 10.1021/acs.jpcc.7b06129
J. Phys. Chem. C 2017, 121, 17538−17545


